

Portable Wafer Probe Station PS-5026B

Advanced TLP/HMM/HBM Solutions

1 Features

- Portable manual wafer probe station
500 mm x 500 mm x 500 mm
- Electrically isolated chuck with vacuum interface and wafer backside potential connector
- Trinocular stereo zoom microscope with 80 times magnification and camera interface for chipfots
- Ultra long-life 20000 lx white LED ring light
- Including 5 MP USB video camera
- High reliability
- Low cost

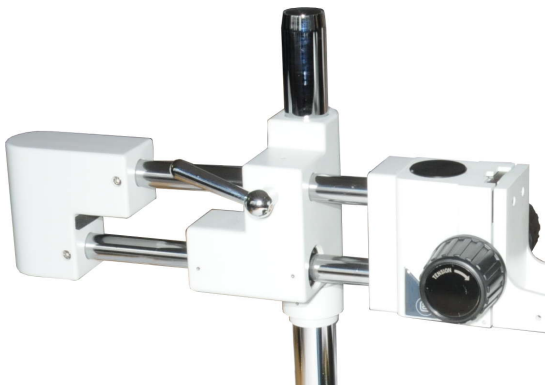


Figure 1: Precision microscope bearing arm



Figure 2: PS-5026B portable wafer probe station

2 System Description

The PS-5026B portable wafer probing station (Fig. 4) enables manual TLP/VF-TLP/HMM wafer-level measurements on up to 300 mm wafers. The probing station can also be used for RF, S-parameter and DC-measurements. Micropositioners with vacuum as well as magnetic base can be attached.

The chuck has a vacuum interface for the wafer and is electrically isolated. A 4 mm connector is used to connect a voltage potential to the wafer backside.

The trinocular microscope has 80 times magnification and is equipped with a camera interface and a bright and ultra long-life 20000 lx LED ring light.

The optional micropositioner kit PHD-3001A (Fig. 3) is electrically isolated and can be customized for various micropositioners.

The PS-5026B is a rugged portable wafer probing solution which has been designed for high reliability, compact size and minimum investment cost.

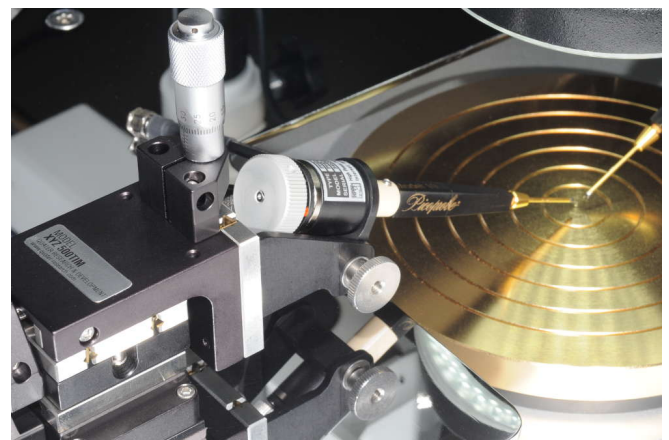


Figure 3: Optional precision micropositioner kit PHD-3001A, customized for Quater XYZ500TIM micropositioner

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Figure 4: PS-5026B portable wafer probe station with 5 MP USB video camera. Optional: precision Picoprobe micropositioner Kit PHD-3001A, two micropositioner from Quater model XYZ500TIM.

3 Specifications

Parameter	Symbol	Limit Values			Unit	Remarks
		Min.	Typ.	Max.		
PS-5026B dimensions	W x D x H	500 x 300 x 500			mm ³	system as shown in Fig. 4
PS-5026B weight	G _S		14		kg	system as shown in Fig. 4
Chuck diameter	d _C		150		mm	up to 300 mm wafers can be attached
Chuck capacitance to GND	C _{C,GND}		70		pF	if chuck is not connected (floating)
Microscope magnification	M	10		80		variable
Microscope white LED light source	LLED			20000	lx	variable

4 Ordering Information

Pos.	Description	Part No.
01	Portable wafer probing station including trinocular microscope, USB camera and LED light	PS-5026B
02	Precision Micropositioner Kit PHD-3001A (Fig. 3), customized for Quater XYZ500TIM micropositioner	PHD-3001A
03	Quater micropositioner XYZ500TIM (please note: two micropositioners are required)	XYZ500TIM
04	Miniature vacuum pump	VP-5026A